

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Confirmation No. 7083

Eiji HASEGAWA

Date: October 27, 2006

Serial No.: 10/768,611

Group Art Unit: 2823

Filed: January 29, 2004

Examiner: Fernando L. TOLEDO

For: SEMICONDUCTOR DEVICE WITH NITROGEN IN OXIDE FILM ON
SEMICONDUCTOR SUBSTRATE AND METHOD OF MANUFACTURING
THE SAME

VIA EFS-WEB

Commissioner for Patents

P.O. Box 1450

Alexandria, Virginia 22313-1450

SUMMARY OF INTERVIEW UNDER 37 C.F.R. § 1.560(b)

Sir:

Pursuant to 37 C.F.R. § 1.560(b) and M.P.E.P. §713.04, applicant's undersigned representative hereby summarizes the personal interview held with Examiner Fernando L. TOLEDO on September 27, 2006.

The applicants' attorney agrees with the Examiner's Summary of the Interview in the record (PTOL-413, September 29, 2006), and submit the following:

(A) A brief description of the nature of any exhibit shown or any demonstration conducted

No exhibits were shown and no demonstration was conducted.

(B) Identification of the claims discussed

Claims 1-23 were discussed.

(C) Identification of specific prior art discussed

All prior art cited in the final rejection was discussed.

(D) Identification of the principal proposed amendments of a substantive nature discussed

As in the file.

(E) The general thrust of the principal arguments of the applicant and the examiner

As in the file.

(F) A general indication of any other pertinent matters discussed

No other matters were discussed.

(G) The general results or outcome of the interview

An agreement was reached.

THIS CORRESPONDENCE IS BEING
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Respectfully submitted,



MAX MOSKOWITZ
Registration No.: 30,576
OSTROLENK, FABER, GERB & SOFFEN, LLP
1180 Avenue of the Americas
New York, New York 10036-8403
Telephone: (212) 382-0700